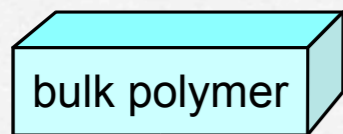


# polymer surfaces

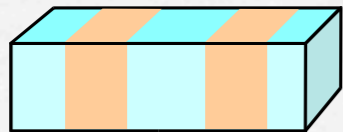
# Classes of Polymer Surfaces

1) as substrate:



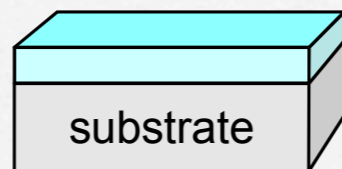
"external" surface

block copolymer



"internal" surface  
→ **interface**

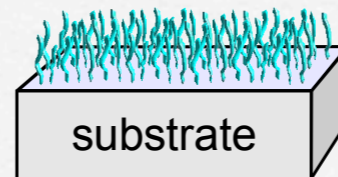
2) as surface layer:



surface & interface

(→ adhesion and cohesion important parameters)

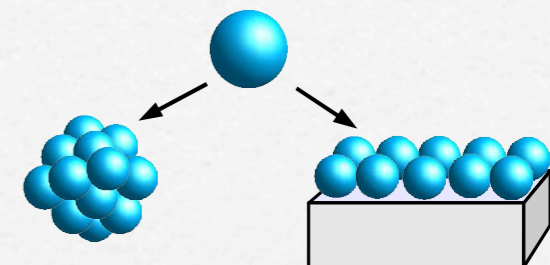
3) as surface molecules:



individual molecules share surface & interface

(→ large gradient of external influence on single molecule possible)

4) as discrete particles:



aggregate

surface layer

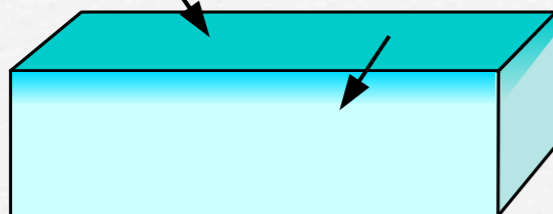
often very large surface-to-volume ratio

(→ substantially different behavior to bulk material)

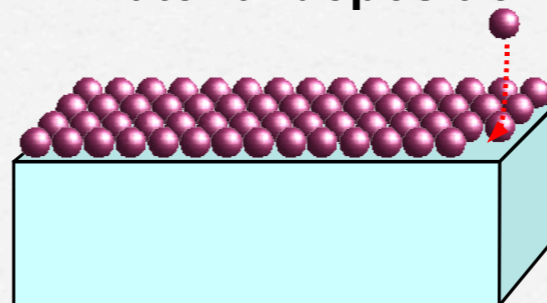
## General Modification Strategies

- surface transformation:

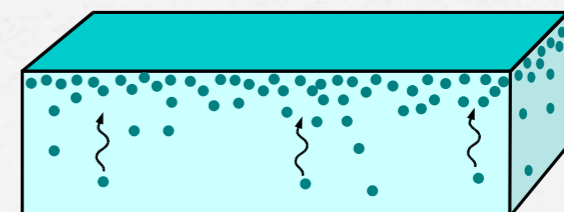
reagents (e.g.  $O_2$ )      energy (e.g.  $h\nu$ ,  $\gamma$ ,  $kT$ )



- film formation by material deposition:

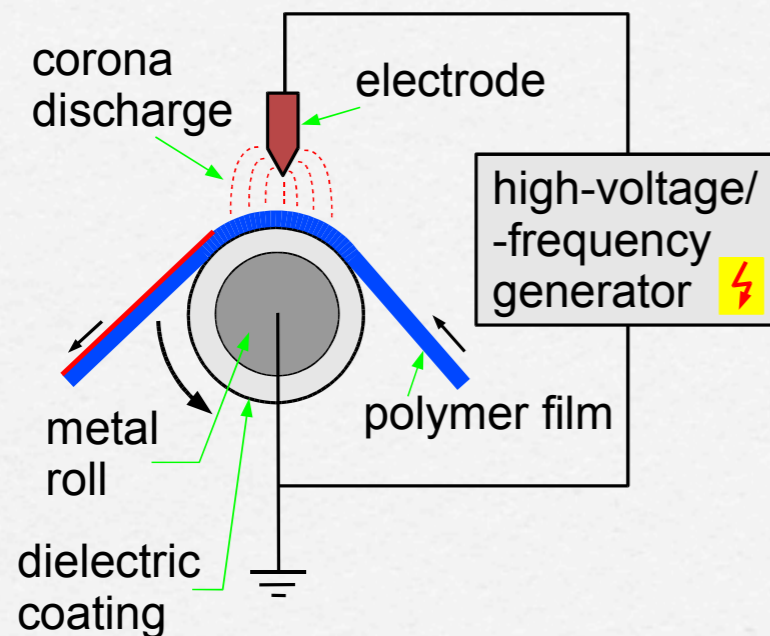


- surface segregation:





# Corona Discharge Treatment



corona discharge glow:



the polymer surface (often polyolefins) is treated with the products (normal pressure plasma) from a corona discharge in ambient atmosphere (about 4000-35000 J m<sup>2</sup>)

the workpiece (usually thin polymer film) is placed between an electrode and a grounded metal roll

electrons are ejected from the electrode by strong electric field

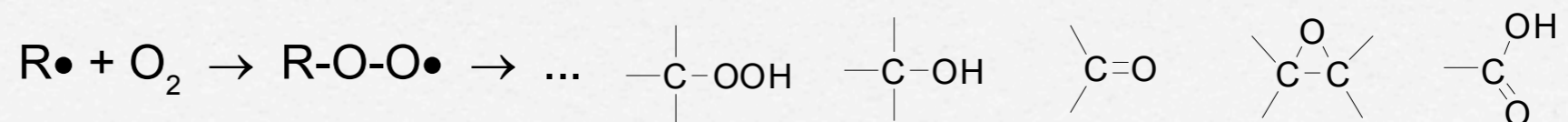
→ these electrons collide with air molecules and the polymer surface to generate **free radicals, ions, photons, excited and reactive intermediates**

→ reactions at the polymer surface can lead to:

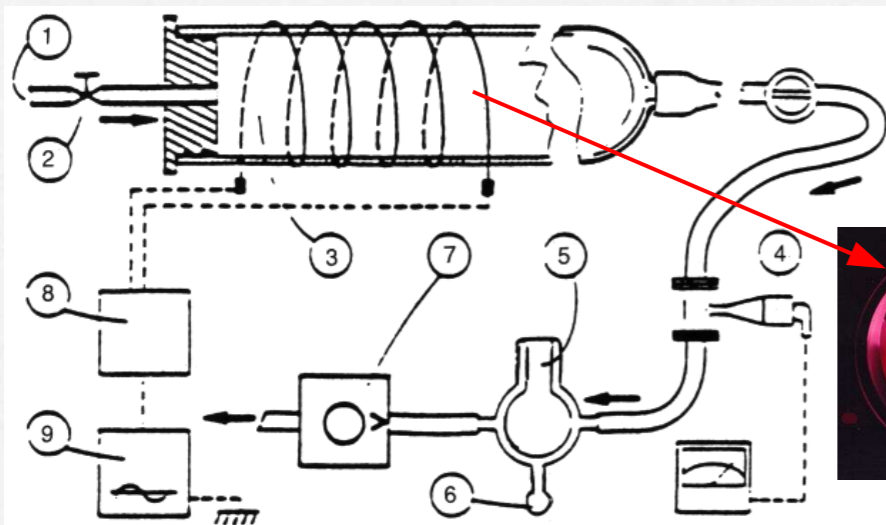
- chain scission,**
- cross-linking,** and
- introduction of **functional groups** (oxidation)

→ promotes adhesion (for gluing or printing) and wetting

## chemical reactions:

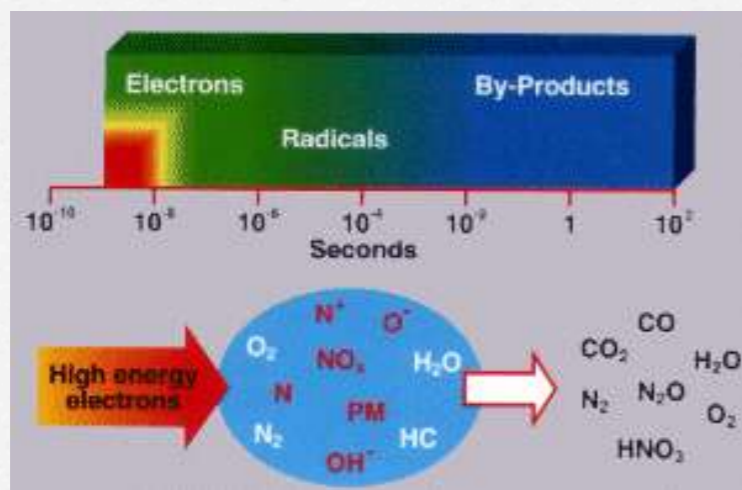


# Plasma Treatment



- 1) gas inlet 2) valve 3) plasma + sample  
 4) pressure gauge 5) liq. N<sub>2</sub> 6) trap  
 7) vac. pump 8,9) matching, RF gen.

reaction cascade in a pulsed normal pressure plasma

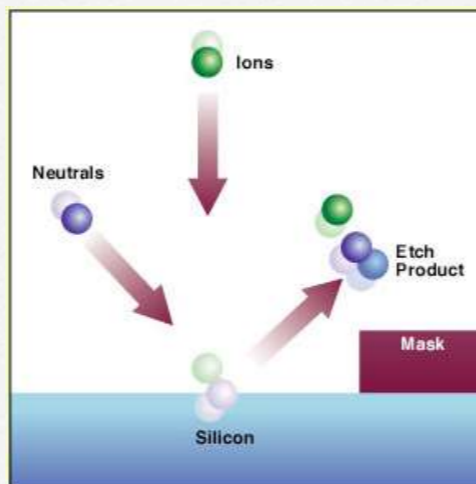


plasma generation in vacuum / low gas pressure *via* electro-magn. high frequency (RF) field (100 kHz, 10-20 MHz, 2.45 GHz) → glow discharge (RFGD)



- the generation of **functional groups** at the polymer surface can be controlled by the choice of plasma **gas** (e.g. H<sub>2</sub>O, O<sub>2</sub>, Ar, N<sub>2</sub>, F<sub>2</sub>, CO<sub>2</sub>, NH<sub>3</sub>)
- free electrons, ions, radicals, and vacuum UV are reactive species (penetration depth few 10 nm)
- functional group generation, material ablation, chain scission, cross-linking

plasma ablation



**process parameter:**

- type of gas, pressure, flow rate,
- excitation power, exc. frequency,
- time of treatment, pulse duration / pause, temp. of substrate
- geometric factors (reactor, sample)

→ improved adhesion (metal films and printing)

# (Wet) Chemical Treatment

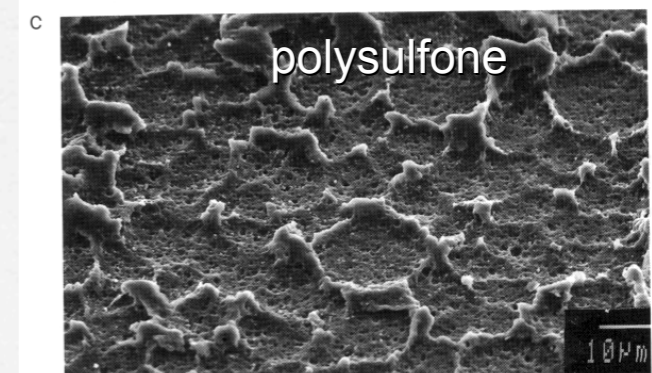
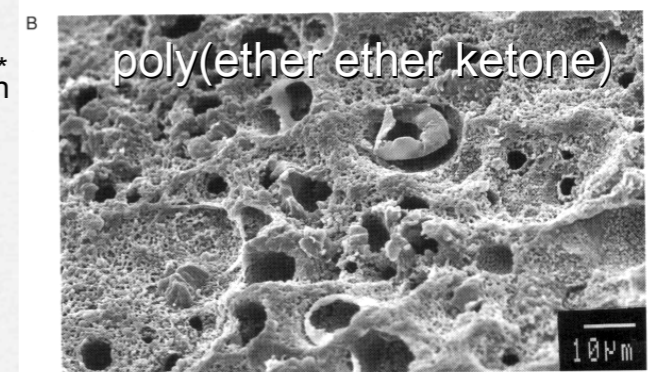
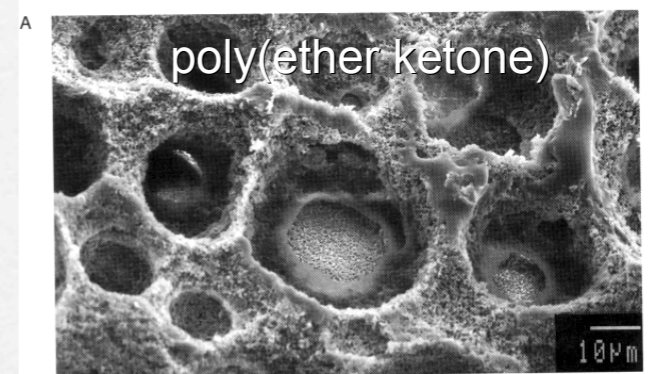
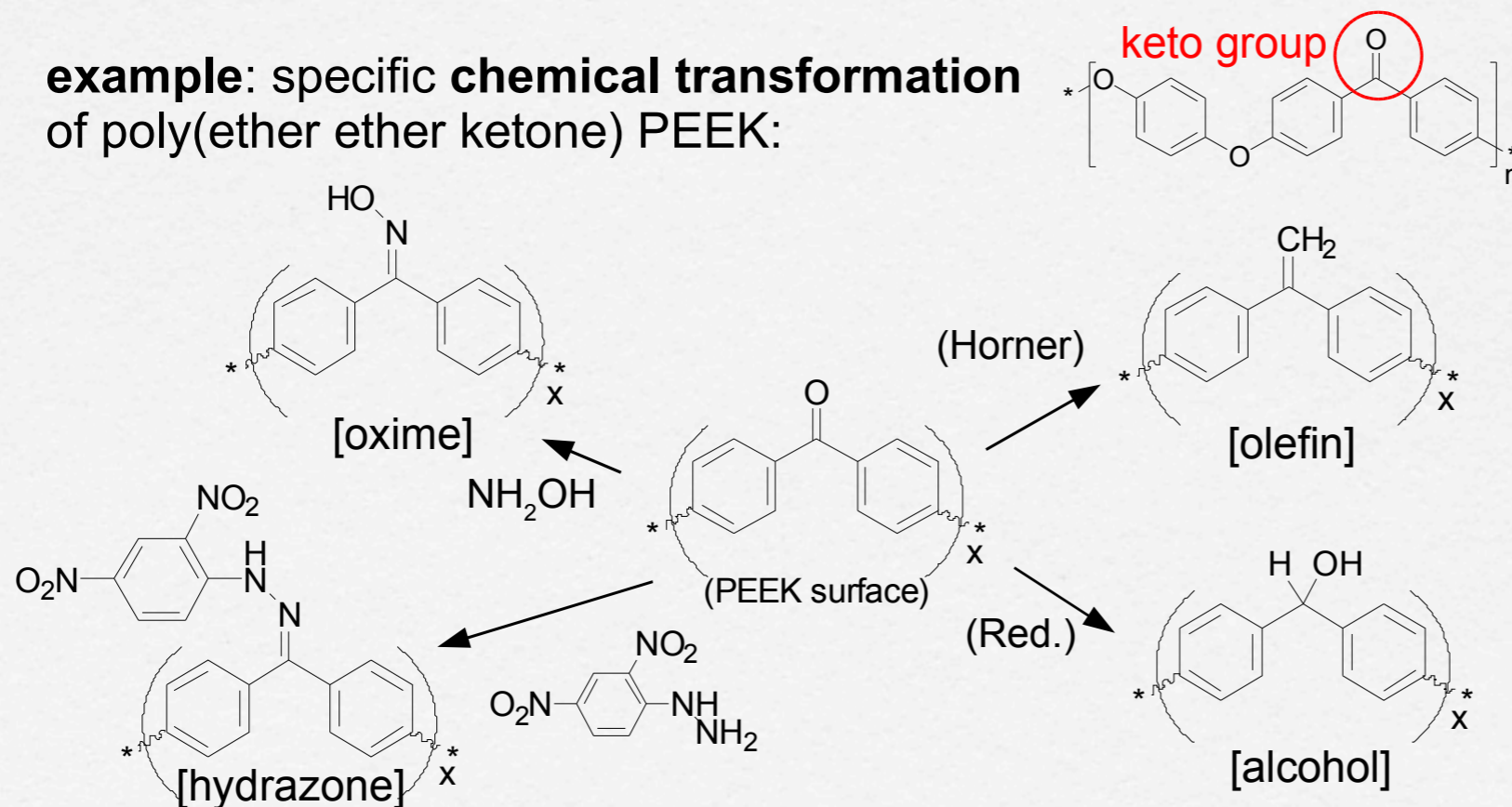
chemical **transformation**, **etching** and **dissolution** of polymer surfaces by active reagents (often oxidizers like  $H_2SO_4$ ,  $KMnO_4$ ,  $CrO_3 / H_2CrO_4$ , or transformation of  $-COOH$  or  $-OH$  with  $SO_2Cl_2$ )

→ often differentiation between **amorphous** (more reactive) and **crystalline** (more inert) regions - enhanced by solvent treatment

→ improves roughness and adhesion of metal film in plating

modification of **surface morphology** by wet chemical etching with  $H_2SO_4$

**example:** specific **chemical transformation** of poly(ether ether ketone) PEEK:

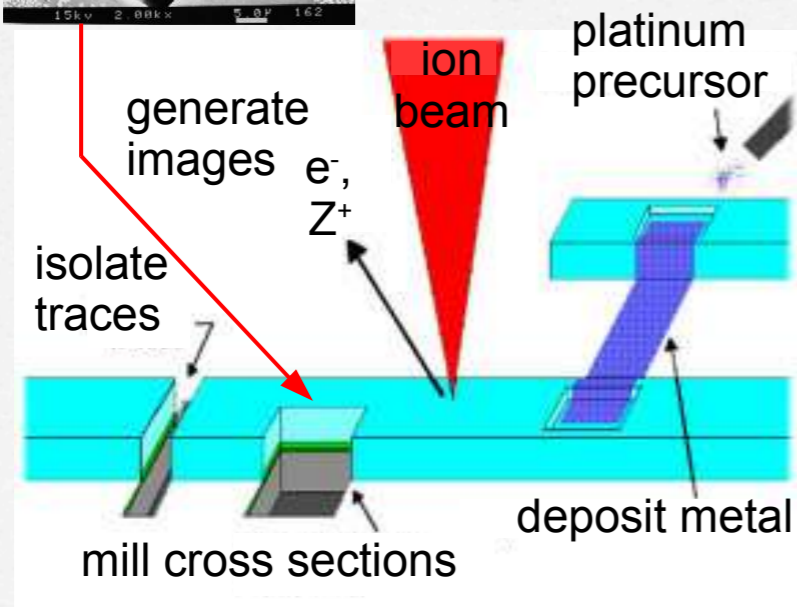
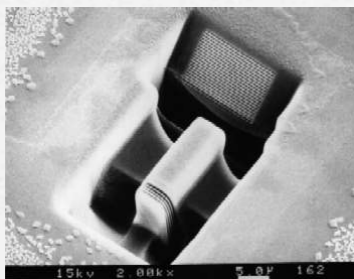


# Ion-Beam Modification

polymer surface is bombarded with **ions** (often focused as beam) to **ablate / mill** the substrate material or to **deposit** new material

→ by **scanning** the focused ion beam **3D structures** with >10 nm resolution can be generated

ion-milled semiconductor



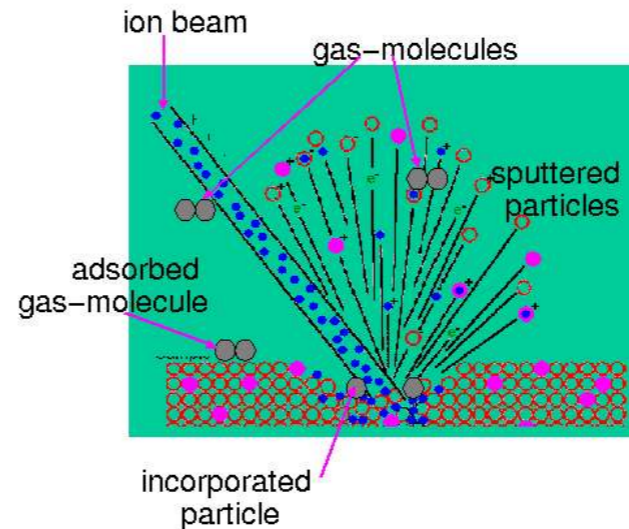
→ ion bombardment of the polymer surface increases the surface **roughness**, generates new **functional groups** and may increase **conductivity**

**process parameter:**

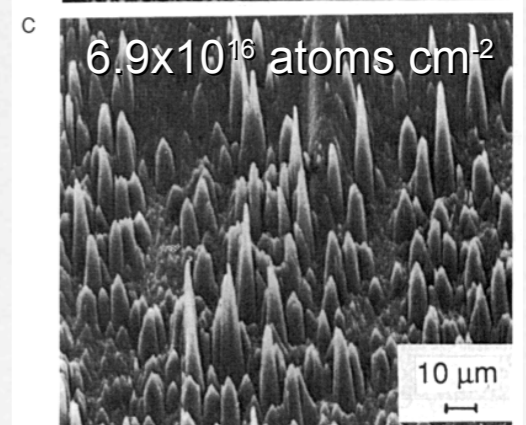
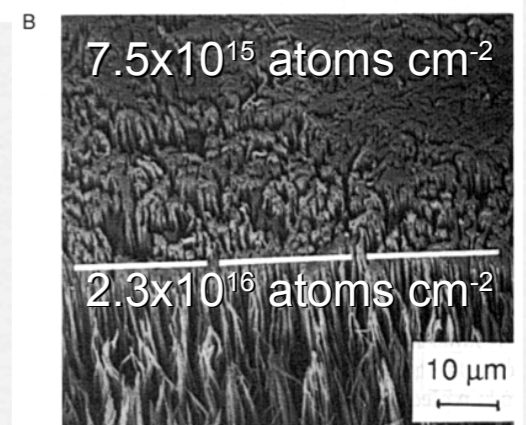
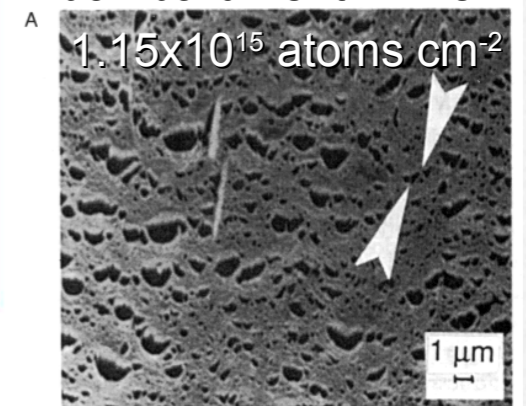
type of ions, ion energy, beam dose  
type of polymer

→ **reactions** at the polymer surface:

- reduction
- oxidation
- chain fragmentation
- cross-linking
- loss of heteroatoms & aromaticity



**surface morphology** of PTFE after ion bombardment w/ Xe

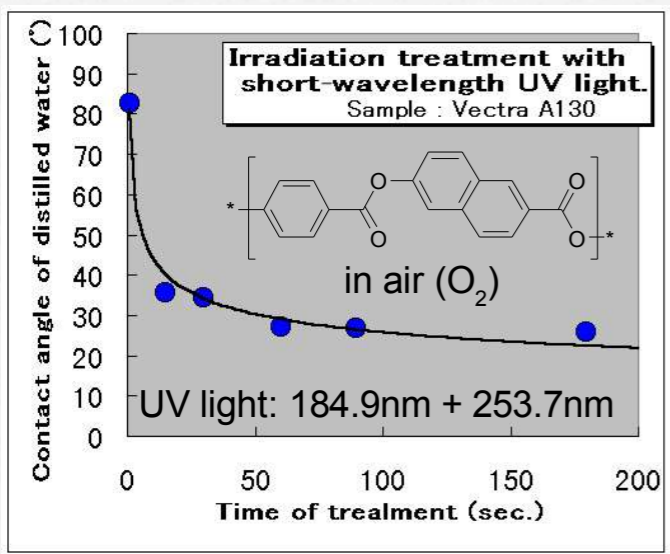
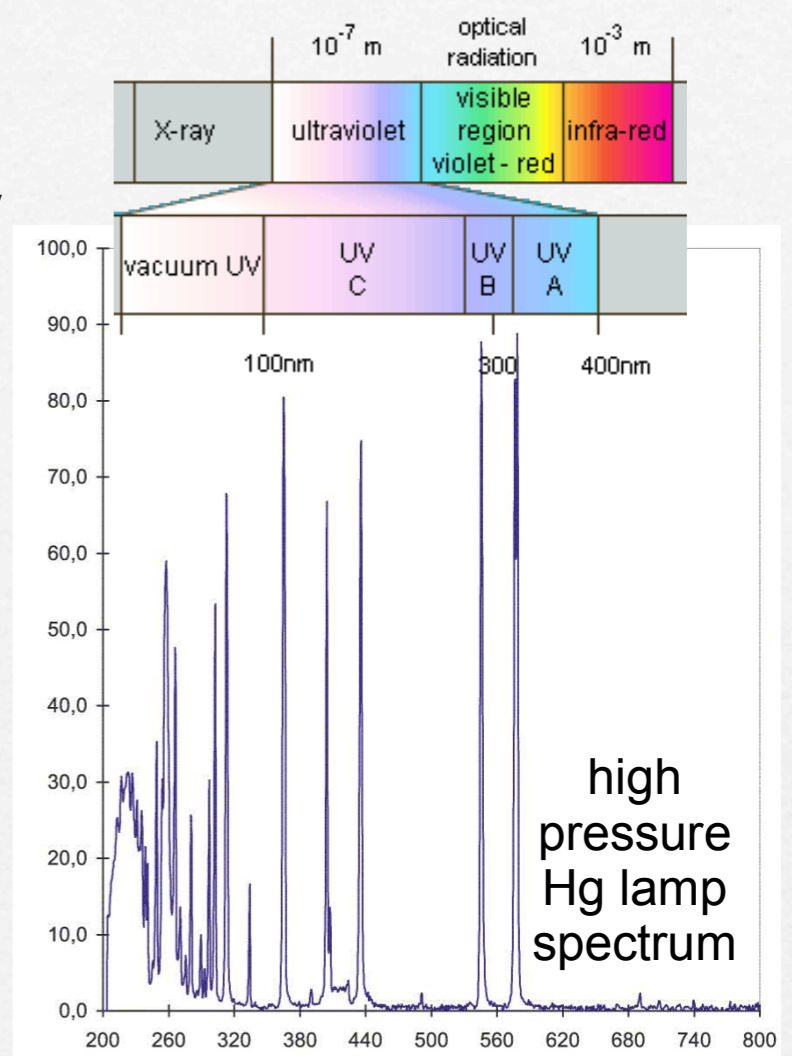




"UV cross-linker"

# T6) UV-Irradiation

irradiation treatment with **short-wavelength UV** light (~180-250 nm) to **activate** polymer surfaces, or to **decompose** dirt on the surface



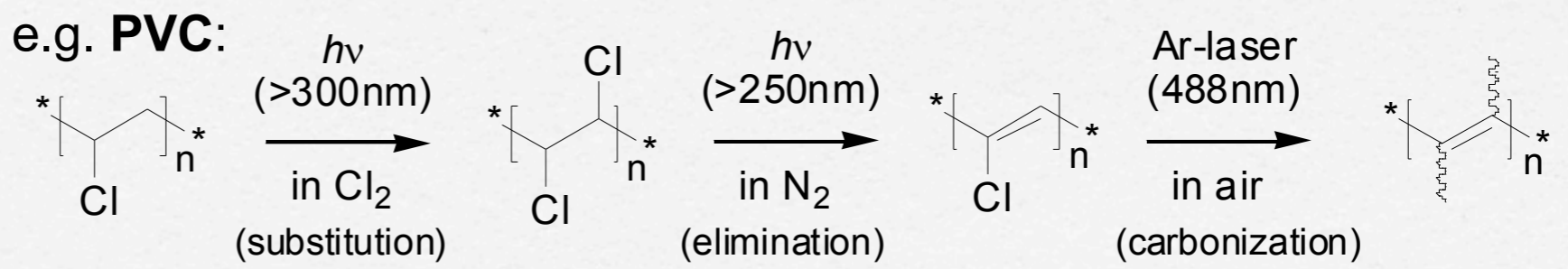
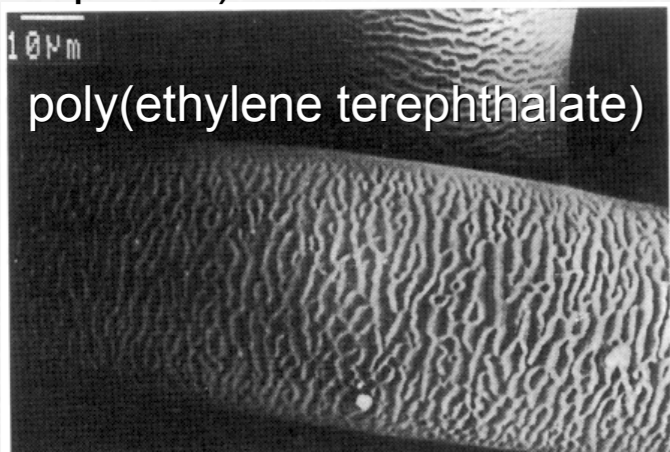
→ **energy** of light induces **chemical reaction** in and near the surface (structuring by irradiation through photomask possible)

**process parameter:**  
wavelength (photon energy), dosis (energy per area), surrounding species / medium

→ possible **reactions:**

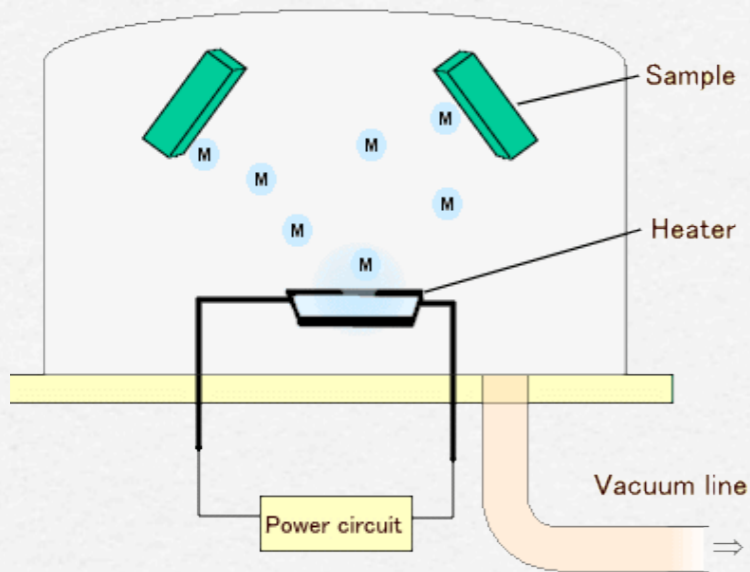
- a) ablation (e.g. activation of oxygen to ozone → volatile ox. prod.)
- b) surface group transformation (e.g. elimination)
- c) introduction of functional groups by photochemical reaction with species from the environment / medium (e.g. -COOH by ox.)

UV laser (248 nm, 60 mJ cm<sup>-2</sup>, 10 pulses)





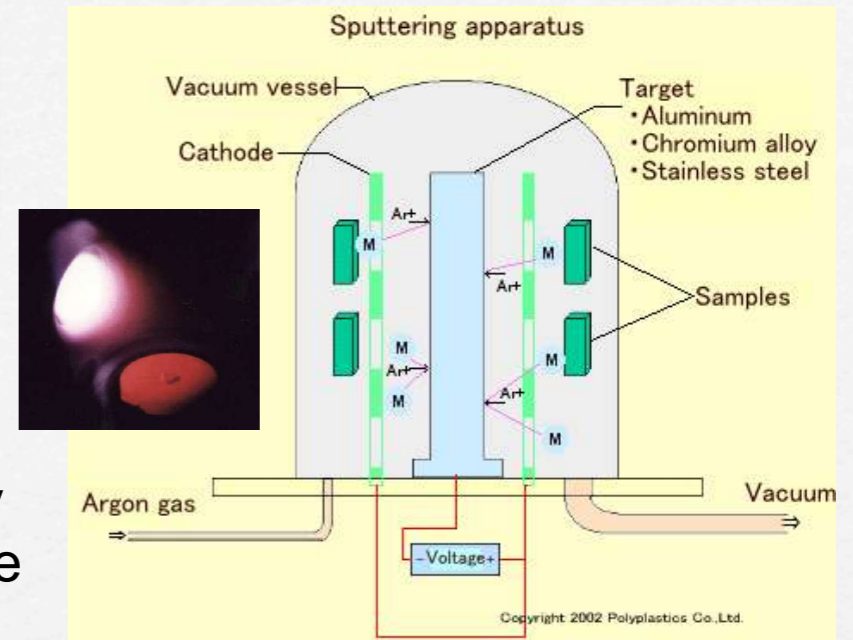
Vacuum metallizing method



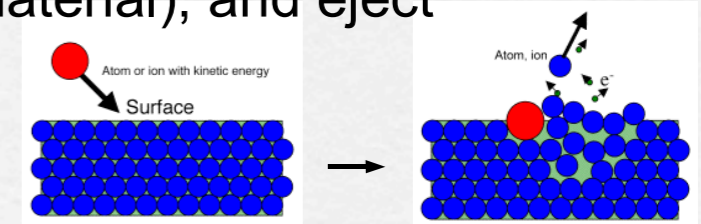
# Material Deposition: D1) Metalization

## a) metal evaporation and sputtering:

metal evaporation in vacuum by heat, e<sup>-</sup>-beam, or glow discharge

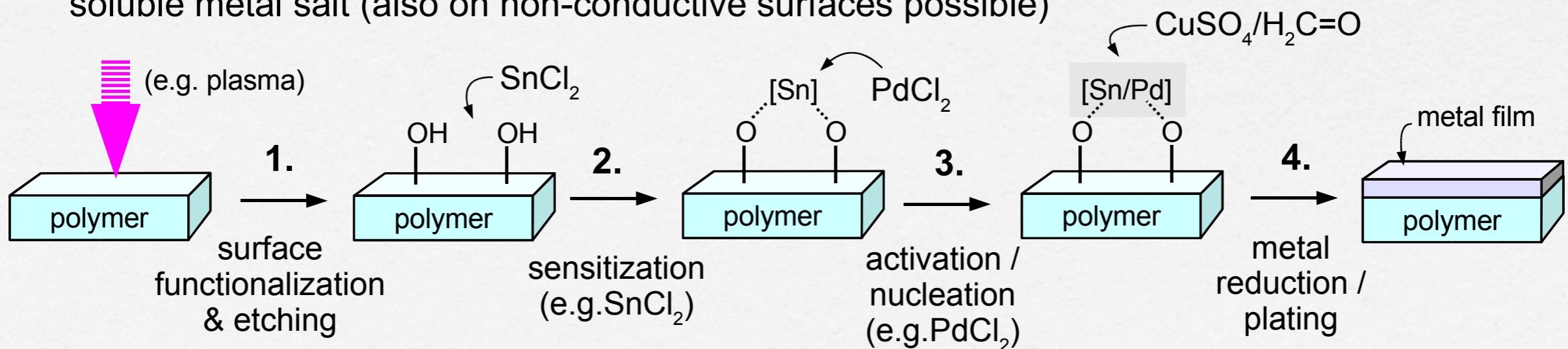


**"sputtering"**: high voltage across a low-pressure gas (e.g. Ar, 5 millitorr) creates plasma (glow discharge), energized plasma ions strike "target" (coating material), and eject atoms from target which travel to and bond with the substrate



## b) electroless / chemical metal deposition (plating):

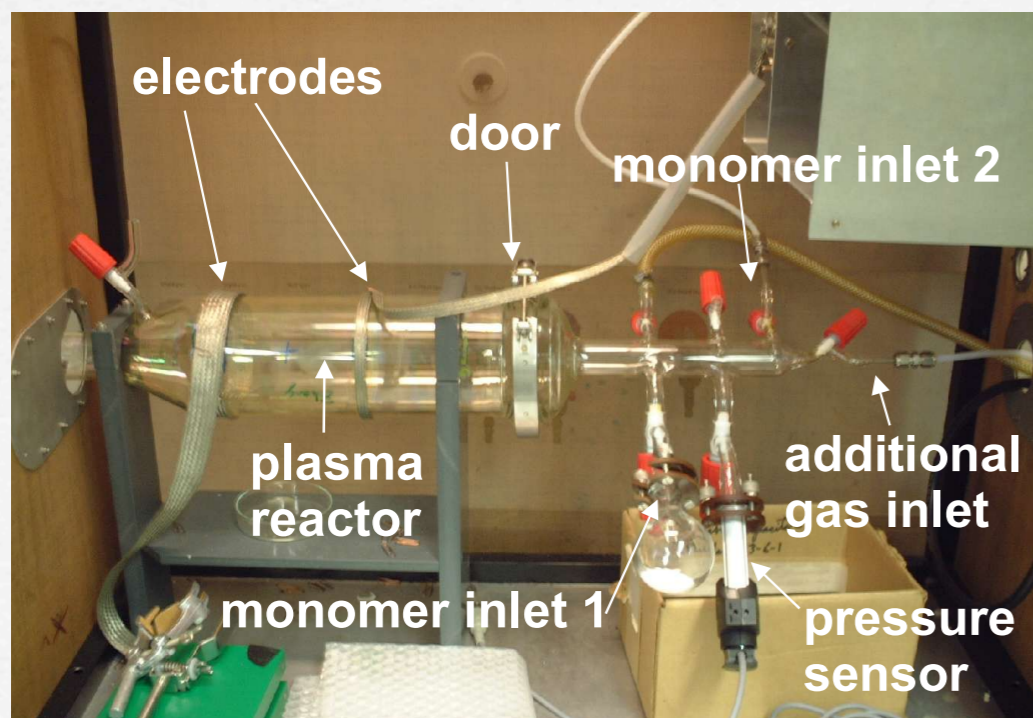
usually deposition of a metal film (e.g. Cu, Ni, Co, Au, Ag, Pd, Pt) by chemical reduction of a soluble metal salt (also on non-conductive surfaces possible)



## D2) Plasma Polymerization

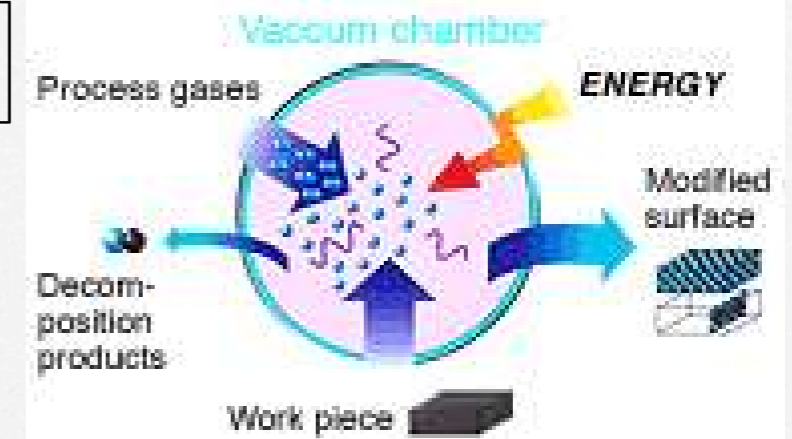
plasma polymerization or plasma enhanced chemical vapor deposition (PECVD) utilizes a similar setup as shown in T3) "Plasma Treatment", but **addition of monomer** through gas phase to generate a **polymer film** at the **substrate surface**

- **CAP-mechanism** (competitive ablation and polymerization: **parallel** processes of **ablation** (material removal) and **polymerization** (material deposition) in plasma of monomer at low gas pressure
- can generate **homogeneous**, highly **cross-linked** polymer films with thicknesses of up to 1  $\mu\text{m}$  ( $\sim 10 \text{ nm min}^{-1}$ )

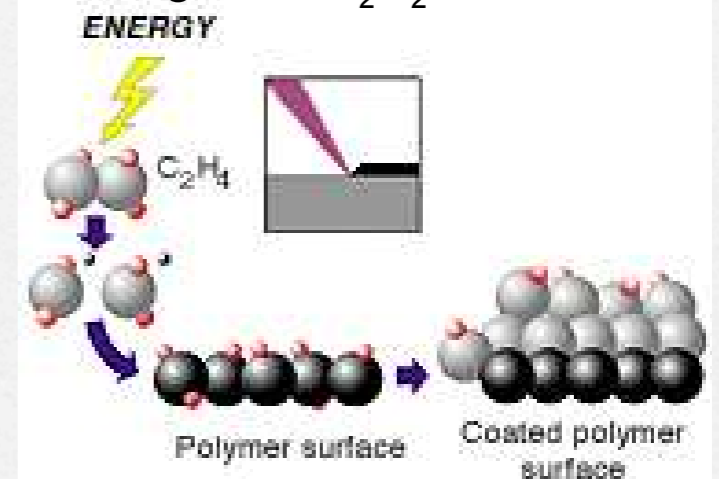


### monomer types:

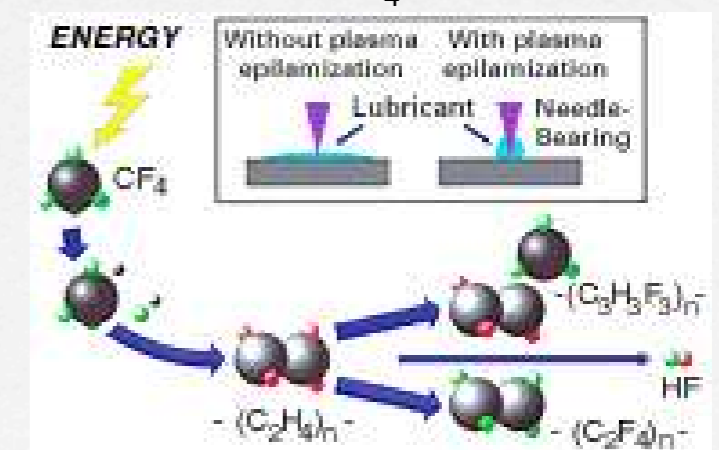
- type I: -C C-, aromatic
- type II: >C=C<, cyclic
- type III: aliphatics (excluded by I & II)
- type IV: O-containing (alcohols, ethers, esters)



generation of **diamond-like** coating from  $\text{C}_2\text{H}_2$



generation of **hydrophobic** coating from  $\text{CF}_4$



# Growth mechanism of plasma polymerization

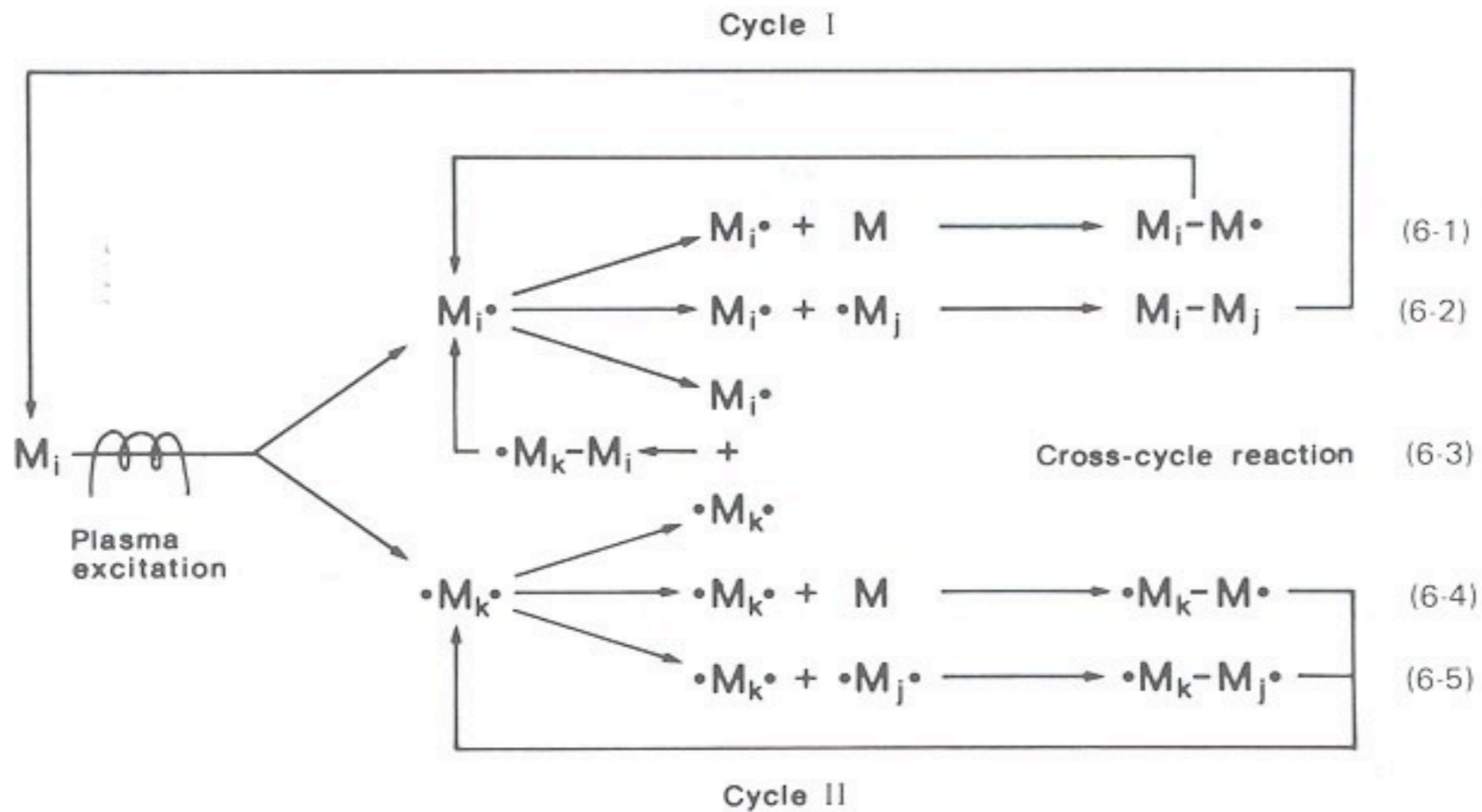


Fig. 6.1 Schematic representation of bicyclic step-growth mechanism of plasma polymerization.



# Applications

| Application       | Substrate  | Monomer(s)                                  | Conditions   | Comments   |
|-------------------|--|---|--|--|
| adhesion promoter | polyaramid   | NH <sub>3</sub>                             |  | Amination of surface; reaction plateau after 1 minute. Better composites achieved  |
| adhesion promoter | polyaramid (Kevlar)  | hexamethyl-disiloxane (HMDSiO)              | 2.45 GHz, LMP reactor, 0.2-1 torr, 100-700 watts       | HMDSiO plasma polymer coating compared to plasma treatment (air, N <sub>2</sub> , NH <sub>3</sub> , N <sub>2</sub> plasmas) for adhesion. HMDSiO plasma polymer yields best adhesion for fabric/epoxy/fabric laminate.                   |
| adhesion promoter | CaCO <sub>3</sub>  | Ar, <i>t</i> -butanol, <i>n</i> -butylamine | microwave, LMP reactor, 0.5-2 torr, 200 watt pulsed    | Ar plasma treatment followed by <i>t</i> -butanol or <i>n</i> -butylamine plasma polymer coating affects acid/base properties of coating thereby improving dispersion of CaCO <sub>3</sub> filler in PVC (acid) and polyethylene (base). |
| adhesion promoter | polyethylene, poly(vinylidene fluoride), poly(tetrafluoroethylene), poly(vinyl chloride) | acetylene                                   | 50 Hz, capacitively coupled, 0.1-0.7 torr, 4.7-42 sccm | Acetylene plasma polymer results in better adhesion of all substrates to epoxy because of increased hydrophilicity <i>and</i> surface of increased roughness.  |

# Applications

Material transport through plasma polymers.

Barrier and protective films.

Electrical applications.

Abrasion resistant coatings.

Optical applications.